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MEMC 98-4650 (2293)  
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Gregory Wilson, et al.

Serial No. 09/608,302

Filed June 30, 2000

Confirmation No. 9819

For A METHOD AND APPARATUS FOR FORMING A SILICON WAFER WITH A  
DENUDED ZONE

January 14, 2002

TO THE COMMISSIONER OF PATENTS AND TRADEMARKS,

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**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

In accordance with 37 C.F.R. 1.97 and 1.98 and MPEP 609, and in compliance  
\* with the duty of disclosure set forth in 37 C.F.R. 1.56, applicants submit copies of the  
references listed on the attached PTO/SB/08A for consideration by the Patent and  
Trademark Office in the above-entitled application and to be made of record therein.

I certify that each item contained in this statement was first cited in a  
communication from a foreign patent office in a counterpart foreign application not more  
than three months prior to the filing of this statement.

Respectfully submitted,

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